IN THE CLAIMS:

Please cancel Claim 1 without prejudice to or disclaimer of the subject matter presented therein. Please amend Claims 2 to 5, 7, and 8 and add new Claim 9 as shown below. The claims, as pending in the subject application, read as follows:

1. (Cancelled)

2. (Currently Amended) ~~A composition for forming piezoelectric film~~ The method according to ~~claim 1~~ claim 5, wherein said metal compound is an organometallic compound.

3. (Currently Amended) ~~A composition for forming piezoelectric film~~ The method according to ~~claim 1~~ claim 5, wherein the total content of the elemental halogens, halogen ions and halogen compounds contained in said sol-gel composition is 3 ppm or less.

4. (Currently Amended) ~~A composition for forming piezoelectric film~~ The method according to ~~claim 1~~ claim 5, wherein said dispersoid comprises at least titanium, zirconium and lead ~~are contained as said metal~~.

5. (Currently Amended) A ~~manufacturing~~ method of manufacturing a piezoelectric film, comprising:

a process for preparing, by performing a plurality of preparation operations at different times, a ~~forming a coating film by applying onto a substrate said~~ sol-gel composition for forming a piezoelectric element, wherein ~~film in which~~ the total content of the elemental halogens, halogen ions and halogen compounds contained in ~~the~~ said sol-gel composition ~~comprising the dispersoid obtained from the metal compound~~ is 10 ppm or less, and wherein the sol-gel composition comprises a dispersoid obtained from a metal compound;

a process for forming a coating film by coating a substrate with said sol-gel composition;

a process for drying said coating film; and

a process for obtaining ~~a~~ said piezoelectric film by baking said dried coating film.

6. (Original) A piezoelectric element comprising a piezoelectric film sandwiched between a lower electrode and an upper electrode, wherein said piezoelectric film is produced by the method according to claim 5.

7. (Currently Amended) ~~A~~ The piezoelectric element according to claim 6, wherein the total content of the elemental halogens, halogen ions and halogen compounds contained in said piezoelectric film is 10 ppm or less.

8. (Currently Amended) An ink jet recording head, comprising a pressure chamber ~~communicating~~ communicated with an ink jet orifice, a vibrating plate arranged in

a manner corresponding to said pressure chamber, ~~a~~ the piezoelectric element according to claim 6 arranged in a manner corresponding to said vibrating plate, wherein the ink in said pressure chamber is jetted from said ink jet orifice owing to ~~the~~ a volume change within said pressure chamber caused by said piezoelectric element arranged in a manner corresponding to said vibrating plate.

9. (New) The method according to claim 5, wherein said plurality of preparation operations comprises different preparation operations.